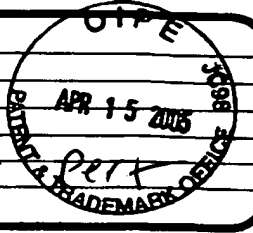


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INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Application Number	10/725,083
				Filing Date	12/02/2003
Date Submitted: April 15, 2005				First Named Inventor	Tadahiro OHMI
				Group Art Unit	2826
(use as many sheets as necessary)				Examiner Name	Forde, Remmon R.
				Attorney Docket Number	039262-0115
Sheet	1	of	1		



U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
SP	B1	2002/0052096	A1	ZHANG et al.	05-02-2002	
EP	B2	2002/0045358	A1	SUZUKI	04-18-2002	

FOREIGN PATENT DOCUMENTS								
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NON PATENT LITERATURE DOCUMENTS			
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SP	B3	MEURIS et al., "The Relationship of the Silicon Surface Roughness and Gate Oxide Integrity in NH4OH/H2O2 Mixtures, Japanese Journal of Applied Physics, Vol. 31, No. 11A, Part 2, Nov. 1992, XP000414884.	
EP	B4	MIYASHITA et al., "Dependence of Thin Oxide Films Quality on Surface Micro-Roughness," 1991 Symposium on VLSI Technology, 28-30 May, 1991, Oiso, Japan, XP010296557.	

Examiner Signature	<i>Eric Perz</i>	Date Considered	2-10-06
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